



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q78469

Satoshi YAMAMOTO, et al.

Appln. No.: 10/736,581

Group Art Unit: 2812

Confirmation No.: 4481

Examiner: Lynne Ann GURLEY

Filed: December 17, 2003

For: METHOD OF FORMING A PENETRATION ELECTRODE AND SUBSTRATE
HAVING A PENETRATION ELECTRODE

RESPONSE TO RESTRICTION REQUIREMENT


Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 27, 2004 in which the Examiner has required a restriction, Applicant responds by electing Group I, *i.e.*, claims 1-11, drawn to a method of making a semiconductor device. This election is made without prejudice to the filing of a divisional application directed to the non-elected claims.

Prompt and favorable action on the elected claims is now respectfully requested.

Respectfully submitted,


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Date: August 13, 2004